I hereby certify that this correspondence for Application Serial 10/613,620 is being sent electronically via EFS-WEB transmission to Technology Center 1762: Examiner Bret P. Chen, Facsimile Number: (571) 273-8300 on March 26, 2007.

/Kevin E. Kuehn/
Kevin E. Kuehn, Reg. No. 51,904

March 26, 2007

Date

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

David C. Fairbourn

Serial No:

10/613,620

Filing Date:

July 3, 2003

Art Unit:

1762

Examiner:

Bret P. Chen

Title:

SIMPLE CHEMICAL VAPOR DEPOSITION SYSTEM AND

METHODS FOR DEPOSITING MULTIPLE-METAL ALUMINIDE

**COATINGS** 

Confirmation No.:

4378

Attorney Docket:

MTCL-09

Cincinnati, Ohio 45202

March 26, 2007

Mail Stop Amendment Commissioner of Patents P.O. Box 1450 Alexandria, VA 22313-1450

## **SUPPLEMENTAL AMENDMENT UNDER 37 CFR § 1.111**

Sir:

In follow-up to the Amendment Under 37 CFR § 1.111 filed on January 12, 2007, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 12 of this paper.